

Summary

5 According to a first aspect, the present invention relates to a device for depositing
a high temperature superconductor onto a substrate in vacuum comprising a
refilling device for containing a stock of high temperature superconductor
material, an evaporation device, that evaporates the high temperature
10 superconductor material within an evaporation zone by means of an energy
transferring medium, and a conveyor that transports the high temperature
superconductor material continuously from the refilling device to the evaporation
zone in such a way that the high temperature superconductor material delivered
into the evaporation zone is evaporated essentially without residues.

15 According to a further aspect, the present invention relates to a method to
evaporate a high temperature superconductor coating onto a substrate in vacuum,
comprising the steps of continuous delivery of granular high temperature
superconductor material into an evaporation zone and the operation of a beam of
an energy transferring medium, so that the delivered granulate is evaporated in the
20 evaporation zone essentially without residues.

(Fig. 1)

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